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INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Application Number		10695620		
	Filing Date		2003-10-27		
	First Named Inventor Alexa		xander Kadyshevitch		
(Not for submission under 37 CFR 1.99)	Art Unit		2881		
,	Examiner Name	David A. Vanore		\	
	Attorney Docket Numb	er	40006317-0045-552		

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Examiner Initial*	Cite No	Patent Number	Kind Code ¹	Issue Date	Name of Patentee or Applicant of cited Document	Pages,Columns,Lines where Relevant Passages or Relevant Figures Appear
DV	1	4578279		1996-03-25	Zingher	
DV	2	4902964		1990-02-20	Lee	
DV	3	5150185		1992-09-22	Yamada	
DV ·	4	5637186		1997-06-10	Liu et al.	
DV	5	5736863		1998-04-07	Liu	
DV	6	5897710		1999-04-27	Sato et al.	
DV	7	5903011		1999-05-11	Hatanaka	
DV	8	6232787		2001-05-15	Lo et al.	

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		, ,				
9	6235634		2001-05-22	White et al.	1 1 1 1	
10	6236222		2001-05-22	Sur Jr. et al.		
11	6407386		2002-06-18	Dotan et al.		
12	6410353		2002-06-25	Tsai		
13	6559662		2003-05-06	Yamada et al.		
14	6614244		2003-09-02	Yamada et al.		
15	6897440		2005-05-24	Yamada		
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Cite No	Publication Number	Kind Code ¹	Publication Date	Name of Patentee or Applicant of cited Document	Releva	Columns,Lines where nt Passages or Relevan Appear
1	20010022345		2001-09-20	Isimoto		
2	20020070738		2002-06-13	Yamada		
	10 11 12 13 14 15 Cite No	10 6236222 11 6407386 12 6410353 13 6559662 14 6614244 15 6897440 n to add additional U.S. Paten Cite No Publication Number 1 20010022345		10 6236222 2001-05-22 11 6407386 2002-06-18 12 6410353 2002-06-25 13 6559662 2003-05-06 14 6614244 2003-09-02 15 6897440 2005-05-24 In to add additional U.S. Patent citation information place. Cite No Publication Number Kind Code1 Publication Date 1 20010022345 2001-09-20	10 6236222 2001-05-22 Sur Jr. et al. 11 6407386 2002-06-18 Dotan et al. 12 6410353 2002-06-25 Tsai 13 6559662 2003-05-06 Yamada et al. 14 6614244 2003-09-02 Yamada et al. 15 6897440 2005-05-24 Yamada 16 to add additional U.S. Patent citation information please click the Add button. 16 U.S.PATENT APPLICATION PUBLICATIONS 17 Cite No Publication Number Kind Code Publication Name of Patentee or Applicant of cited Document 1 20010022345 2001-09-20 Isimoto	10 6236222 2001-05-22 Sur Jr. et al.

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DV	3	20020093350		2002-07-18		Yamada				
DV	4	20020134936		2002-09	9-30	Miyako et al.				
DV	5	20030104639		2003-06	6-05	Kikuchi et al.				
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DV	1	JP 11087451				1999-03-30	Mitsubishi Electric (Corp.		V
DV	2	JP 2000174077				2000-06-23	NEC Corporation			V
DV	3	JP 144155				2001-05-25	Matsushita Electror Industry Corp.	nics		
DV	4	JP 2001338956				2001-07-12	NEC Corporation			
VQ	5	JP 2002083849				2002-03-23	NEC Corporation			
DV	6	JP 2002231780				2002-08-16	Jeol Ltd.			

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7	WO 0180304		A2	2001-10-25	Klatencor Corporation				
8	WO 03067653		A2	2003-08-14	Applied Materials, Inc.				
n to ac	ld additional Foreign Pa	atent Document	citation	information pl	ease click the Add buttor	Add			
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1	International Search Report and Written Opinion for PCT/US2004/014450, September 28, 2004								
2	YACOBI et al., "Microanalysis of Solids", 1994 Plenum Press, New York, Chapters 1, 2 & 4.								
3	Model EKF-1000 Omnicron Nanotechnology GmbH, Taunusstein, Germany, Available at http://www.omnicron.de/ products/ekf1000, 2002								
4	YAMADA, Keizo, "In-Line Contact and Via Hole Monitoring Method Used Electron-Beam-Induced Substrate Current (EB Scope), NEC Research and Development, Nippon Electric Ltd., Tokyo, Japan, vol. 41, no. 4, October 2000 (2000-10), pages 336-340, XP000967723, ISSN: 0547-051X								
5	Invitation to Pay Additional Fees, International Patent Application No. PCT/US03/03494, Applied Materials, Inc., August 19, 2003								
6	International Search Report, International Patent Application No. PCT/US03/03494, Applied Materials, Inc., November 28, 2003								
7	Written Opinion, Interna Inc., January 27, 2005	tional Patent Appl	ication N	No. PCT/US03/0	3494, Applied Materials, Inc	c., Applied Materials,			
	8 Cite No 1 2 3	8 WO 03067653 n to add additional Foreign Particle Include name of the additional Search Research Res	8 WO 03067653 In to add additional Foreign Patent Document NON-PATE Cite No Include name of the author (in CAPITA (book, magazine, journal, serial, symp publisher, city and/or country where pub	8 WO 03067653 A2 To add additional Foreign Patent Document citation NON-PATENT LITE Cite (book, magazine, journal, serial, symposium, publisher, city and/or country where published. 1 International Search Report and Written Opinion of Patent Products/ekf1000, 2002 YACOBI et al., "Microanalysis of Solids", 1994 Please of Products/ekf1000, 2002 YAMADA, Keizo, "In-Line Contact and Via Hole M (EB Scope), NEC Research and Development, Ni (2000-10), pages 336-340, XP000967723, ISSN: Invitation to Pay Additional Fees, International Patent August 19, 2003 International Search Report, International Patent Agency (28, 2003) Written Opinion, International Patent Application No.	8 WO 03067653 A2 2003-08-14 n to add additional Foreign Patent Document citation information pl NON-PATENT LITERATURE DO Cite (book, magazine, journal, serial, symposium, catalog, etc), of publisher, city and/or country where published. 1 International Search Report and Written Opinion for PCT/US2004. 2 YACOBI et al., "Microanalysis of Solids", 1994 Plenum Press, New Model EKF-1000 Omnicron Nanotechnology GmbH, Taunusstein, products/ekf1000, 2002 4 (EB Scope), NEC Research and Development, Nippon Electric Ltd (2000-10), pages 336-340, XP000967723, ISSN: 0547-051X 5 Invitation to Pay Additional Fees, International Patent Application August 19, 2003 6 International Search Report, International Patent Application No. Ed. (28, 2003) Written Opinion, International Patent Application No. PCT/US03/0	B WO 03067653 A2 2003-08-14 Applied Materials, Inc. 1 to add additional Foreign Patent Document citation information please click the Add buttor NON-PATENT LITERATURE DOCUMENTS Cite No Include name of the author (in CAPITAL LETTERS), title of the article (when approprious publisher, city and/or country where published. International Search Report and Written Opinion for PCT/US2004/014450, September 28, 200 YACOBI et al., "Microanalysis of Solids", 1994 Plenum Press, New York, Chapters 1, 2 & 4. Model EKF-1000 Omnicron Nanotechnology GmbH, Taunusstein, Germany, Available at http products/ekf1000, 2002 YAMADA, Keizo, "In-Line Contact and Via Hole Monitoring Method Used Electron-Beam-Indu (EB Scope), NEC Research and Development, Nippon Electric Ltd., Tokyo, Japan, vol. 41, not (2000-10), pages 336-340, XP000967723, ISSN: 0547-051X Invitation to Pay Additional Fees, International Patent Application No. PCT/US03/03494, Applied Materials, Inc. Written Opinion, International Patent Application No. PCT/US03/03494, Applied Materials, Inc.	8 WO 03067653 A2 2003-08-14 Applied Materials, Inc. 1 to add additional Foreign Patent Document citation information please click the Add button NON-PATENT LITERATURE DOCUMENTS Remove Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc), date, pages(s), volume-issue number(s), publisher, city and/or country where published. 1 International Search Report and Written Opinion for PCT/US2004/014450, September 28, 2004 2 YACOBI et al., "Microanalysis of Solids", 1994 Plenum Press, New York, Chapters 1, 2 & 4. 3 Model EKF-1000 Omnicron Nanotechnology GmbH, Taunusstein, Germany, Available at http://www.omnicron.de/products/ekf1000, 2002 4 YAMADA, Keizo, "In-Line Contact and Via Hole Monitoring Method Used Electron-Beam-Induced Substrate Current (EB Scope), NEC Research and Development, Nippon Electric Ltd., Tokyo, Japan, vol. 41, no. 4, October 2000 (2000-10), pages 336-340, XP000967723, ISSN: 0547-051X 5 Invitation to Pay Additional Fees, International Patent Application No. PCT/US03/03494, Applied Materials, Inc., November 28, 2003 6 International Search Report, International Patent Application No. PCT/US03/03494, Applied Materials, Inc., Applied Materials, I		

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DV	8		International Preliminary Examination Report, International Patent Application No. PCT/US03/03494, Applied Materials, Inc., August 19, 2003							
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			f reference considered, whether or not citation is in commance and not considered. Include copy of this fo							
Standard S	T.3). ³ F cument	For Japa by the	TO Patent Documents at <u>www.USPTO.GOV</u> or MPEP 901.04. ² panese patent documents, the indication of the year of the reign of appropriate symbols as indicated on the document under WIPO ion is attached.	of the Emperor must precede the ser	rial number of the patent doc	cument.				